

G1 17 from one side of the inventive megasonic tank 111b to or nearly to the other side of the inventive megasonic tank 111b as shown in FIG. 4, or a net 121 that may be coupled to chamber walls and extend so as to catch falling objects as shown in FIG. 5. It will be understood that the quartz bars 119 and the net 121 are sufficiently thick such that a falling object may not break the quartz bars 119 or the net 121 upon contact therewith.

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Please amend the paragraph beginning on page 8, line 24 as follows:

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G2 Both the quartz bars 119 and the net 121 may protect other components of the inventive megasonic tank 111b in addition to the fragile plate 19. Further, in one aspect, the portion of the extended roller 113 which extends beyond the extended roller 113's wafer supporting portion 18, may be coupled, via a mechanism (e.g., screws, etc.) to the conventional rollers 17 making the conventional rollers 17 easy to retrofit. Finally, the fragile object may comprise objects other than a quartz plate (such as the transducer(s) itself, a sensor, etc.). It will be understood, however, that a lid and/or slideable door is not a barrier.

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In the Claims

Please cancel non-elected claims 1-7, 16, 18-19 and 21.

Please amend claims 8, 13, 17 and 20 as follows:

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AMENDED 8. An apparatus configured to clean a semiconductor substrate, comprising:

G3 a tank configured to contain a liquid the tank having an opening configured to allow a substrate to enter the tank from a position above the tank;